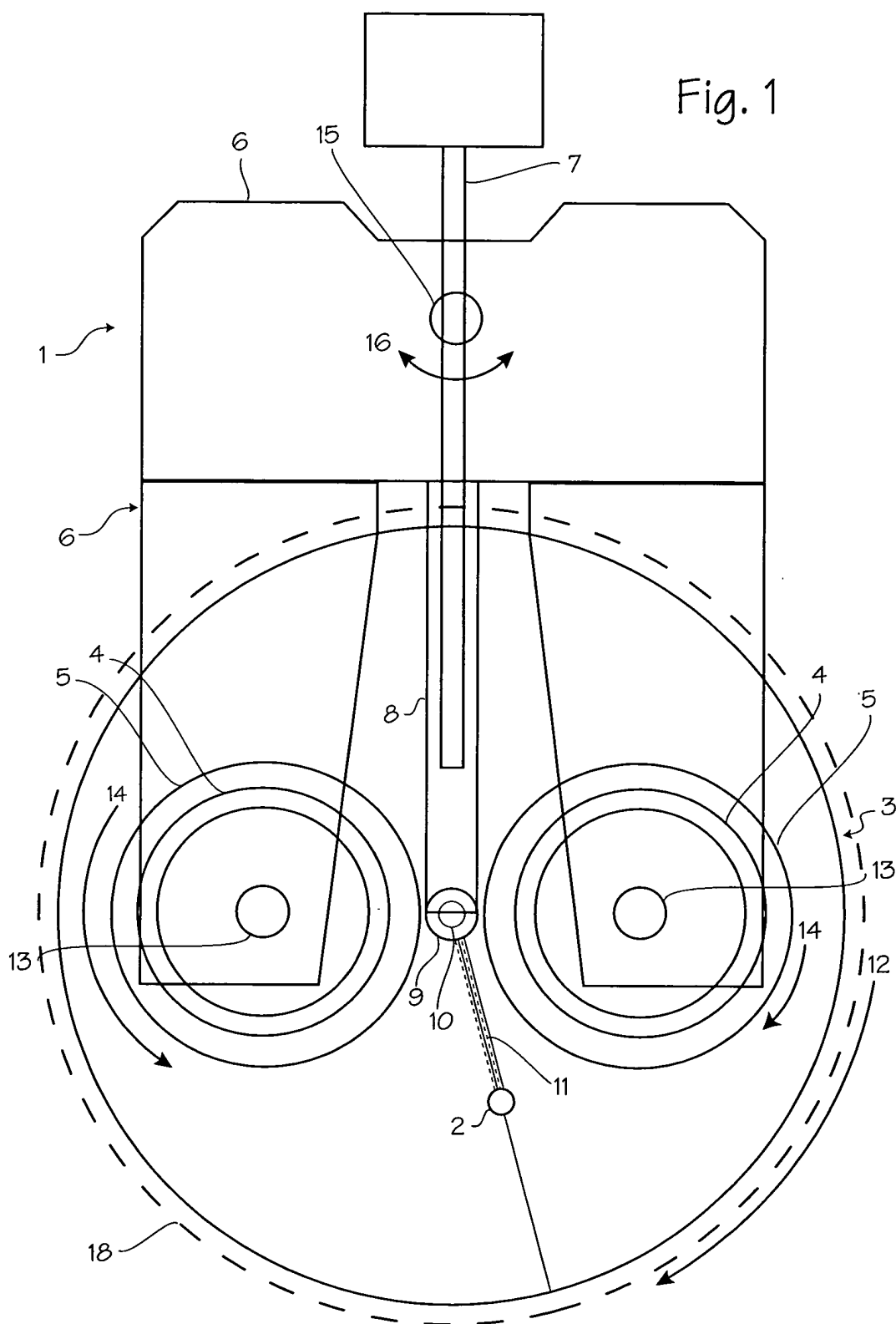


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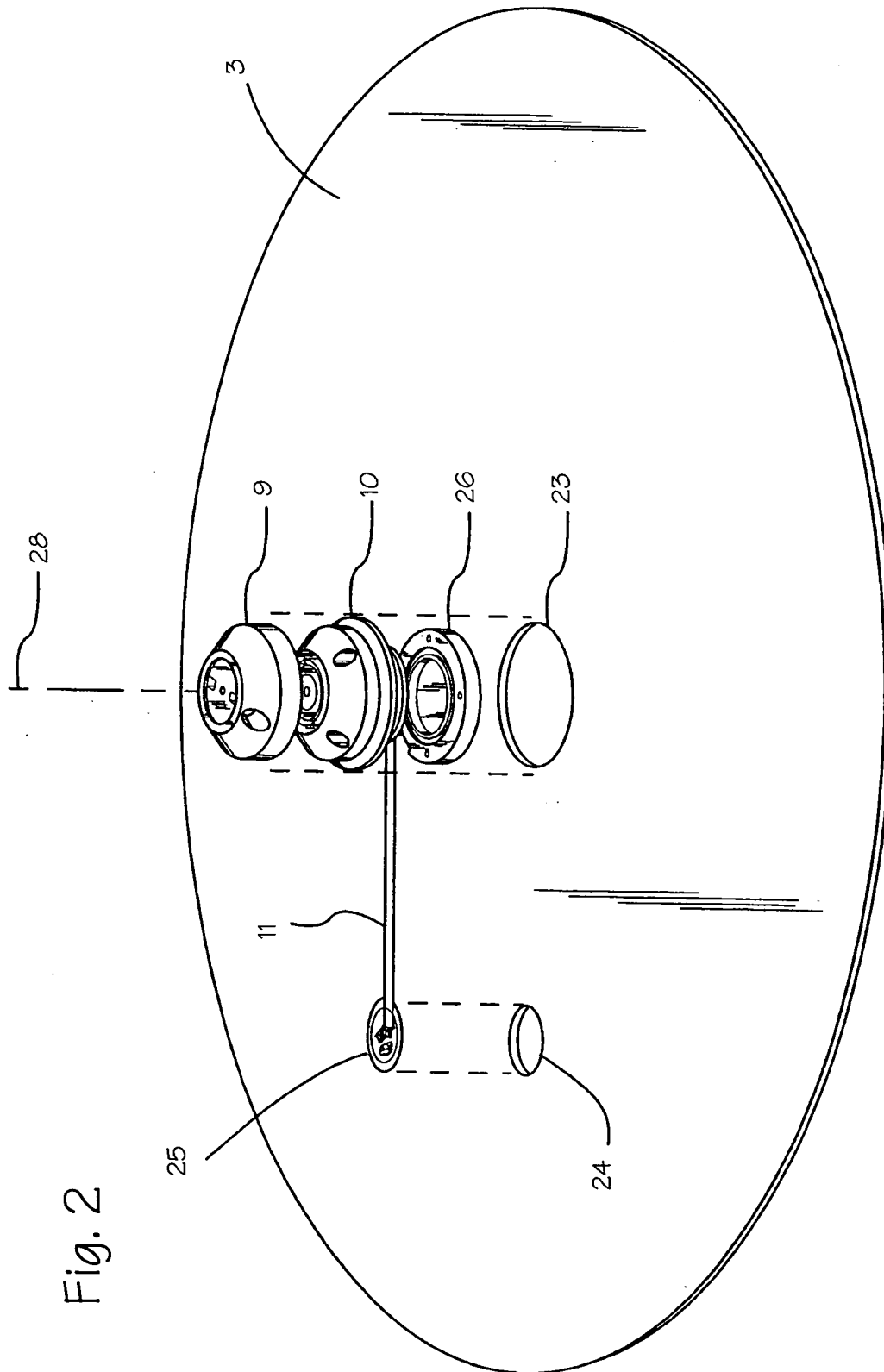


Fig. 2

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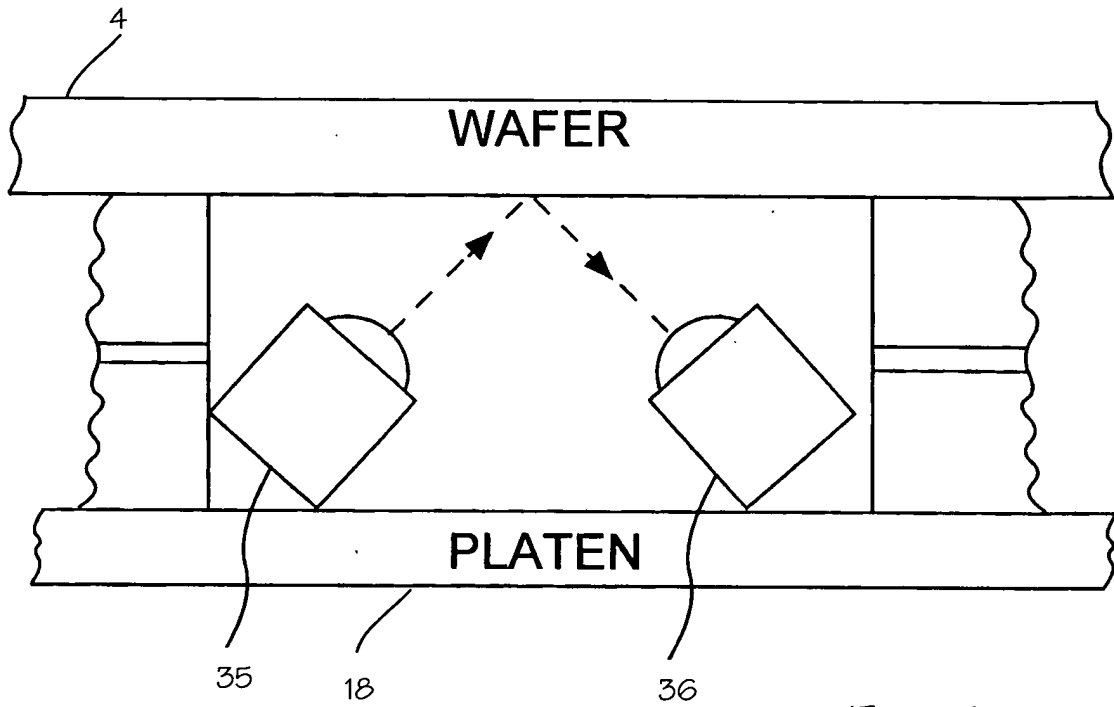


Fig. 4

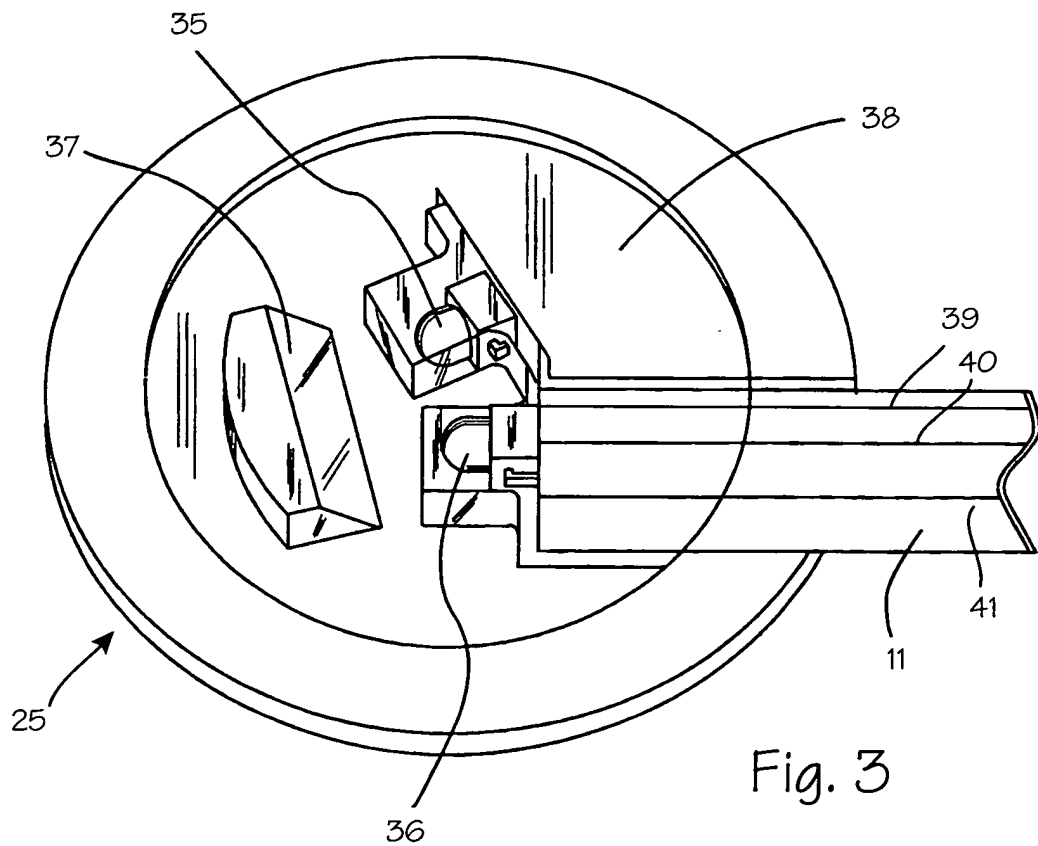
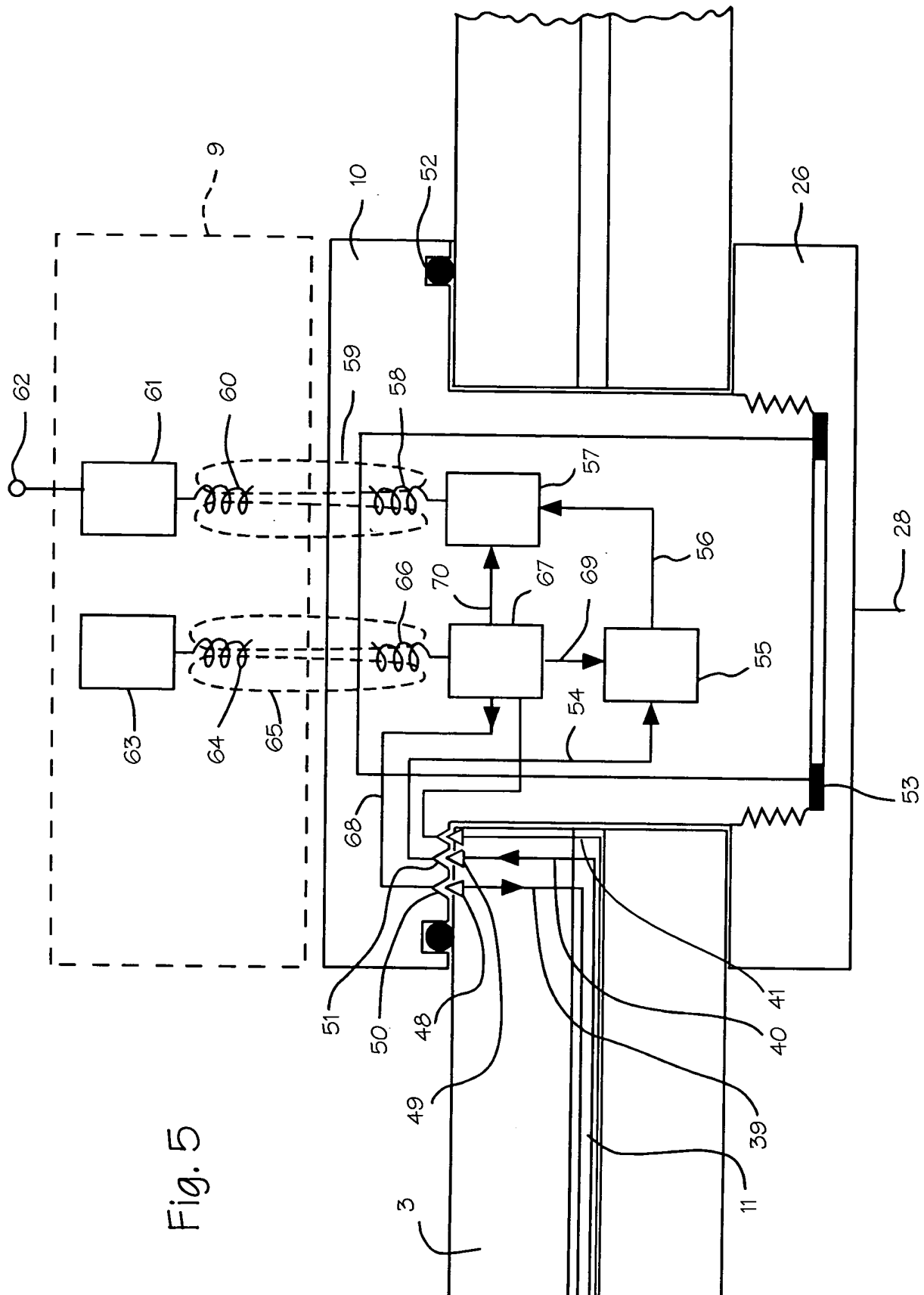


Fig. 3



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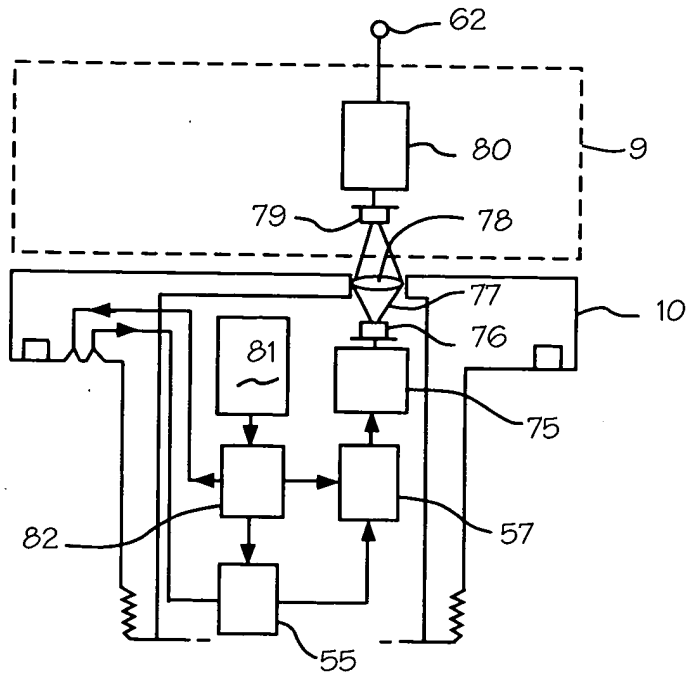


Fig. 6

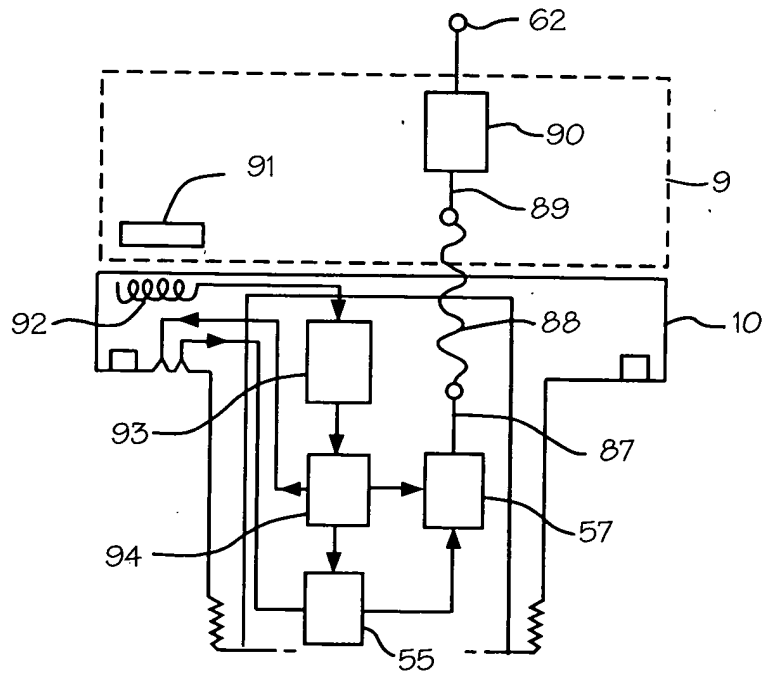
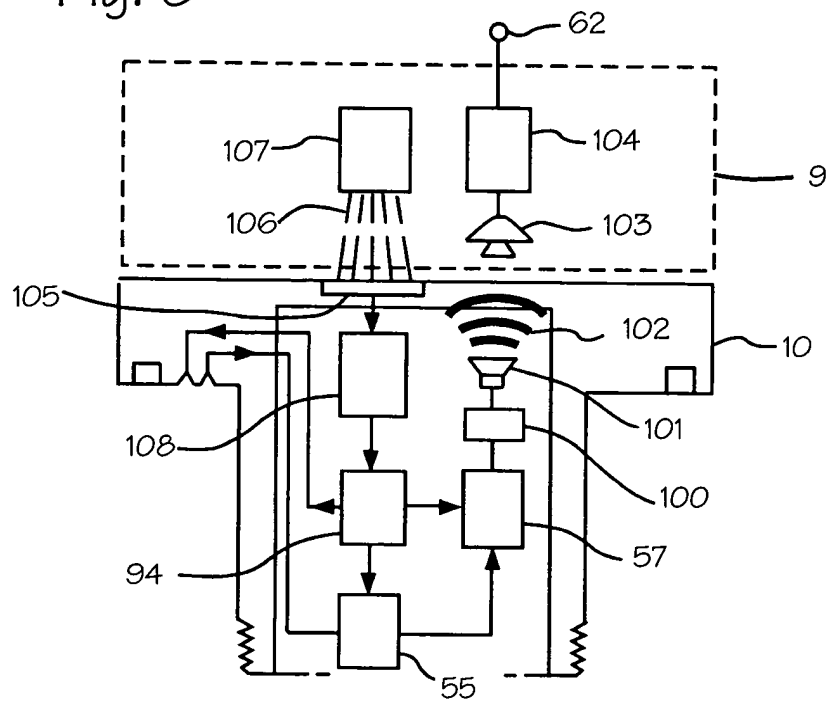


Fig. 7

Fig. 8



[illegible]

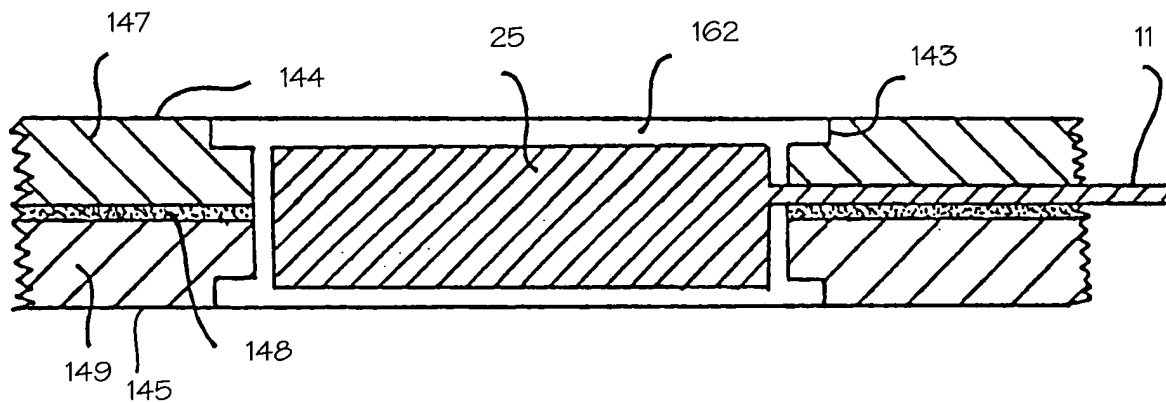


Fig. 11

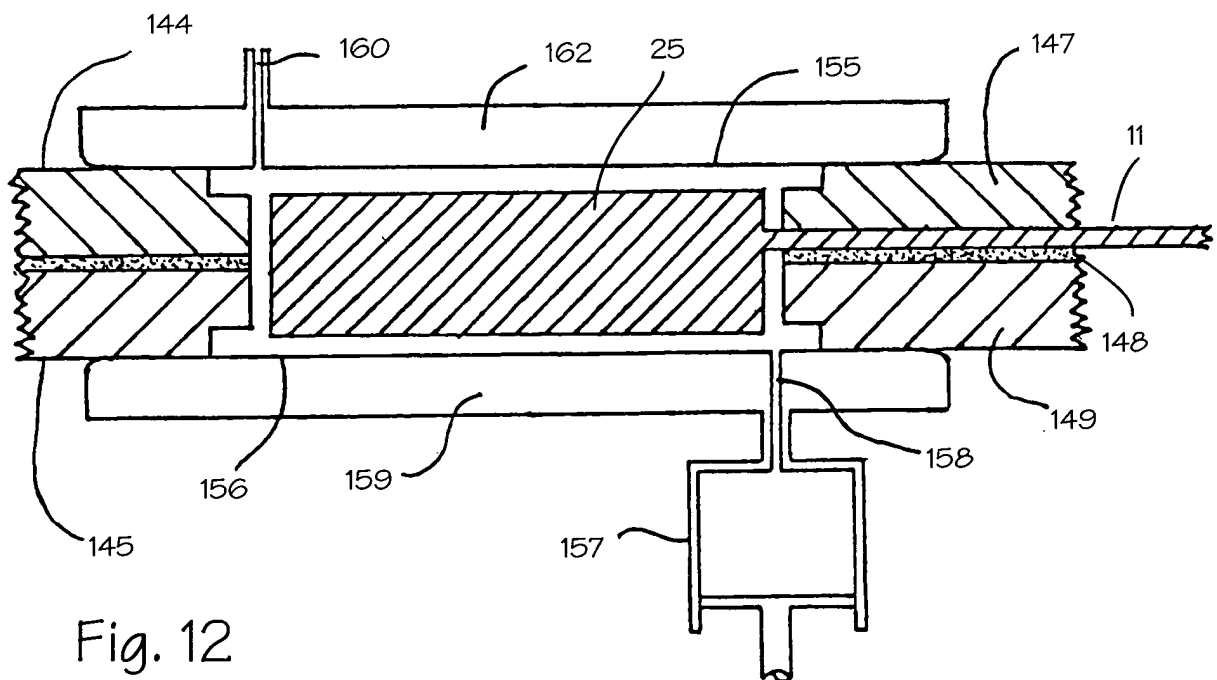
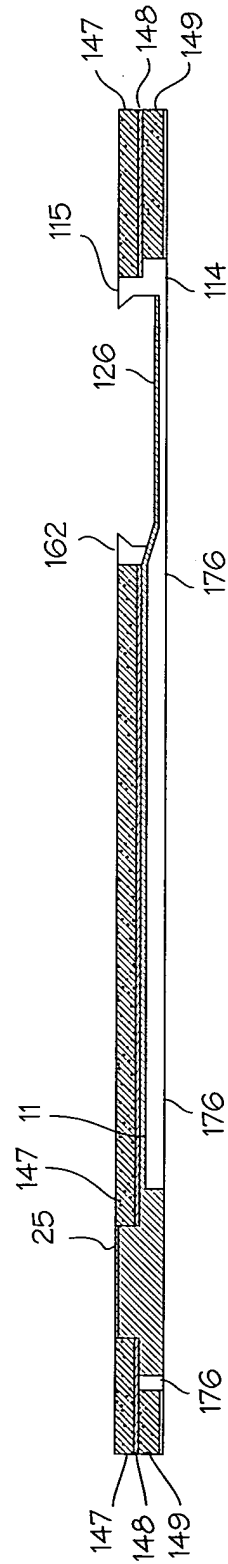


Fig. 12



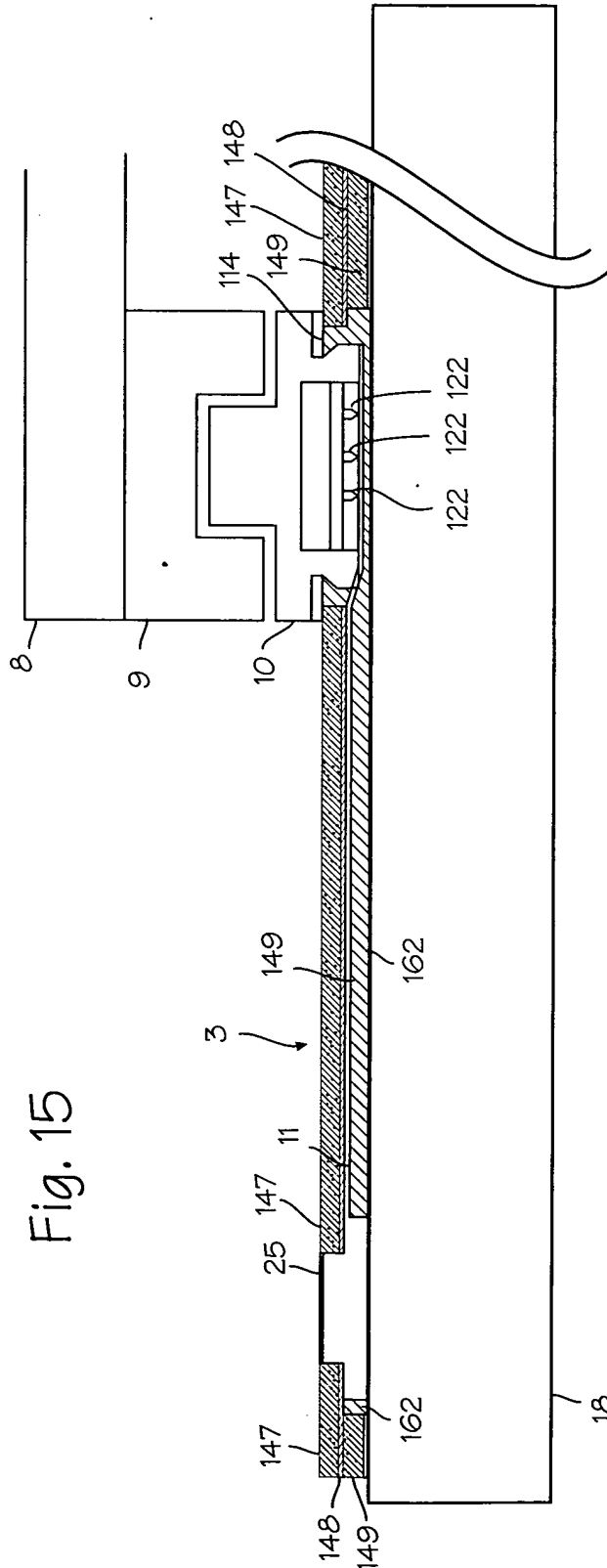


Fig. 16

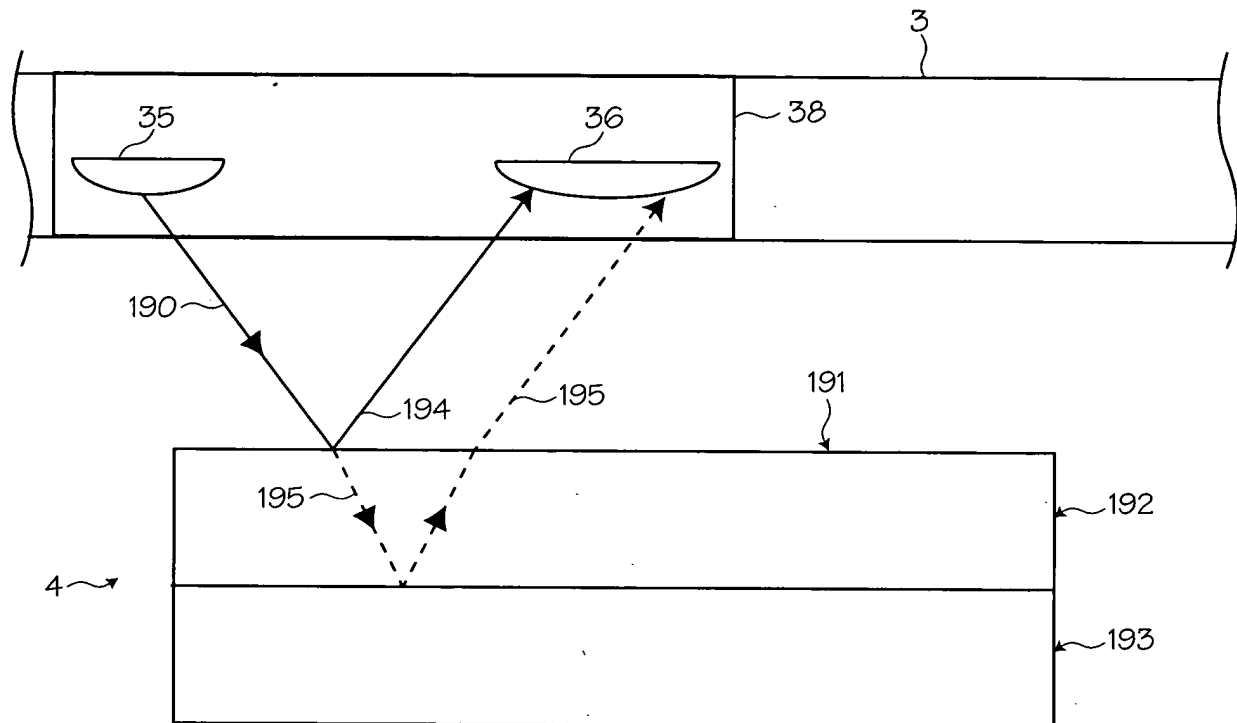


Fig. 17

